## Optical- and Electrical properties of ZnO<sub>x</sub>N<sub>y</sub> Films grown by Atomic Layer Deposition

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ZnO has been attracted as an active channel of thin film transistors (TFTs) for realizing transparent display panels and flexible electronics due to its wide band gap energy ( $E_g = 3.36 \text{ eV}$ ) and low temperature process. However, the electronic mobility of ZnO films is approximately 10 cm<sup>2</sup>V<sup>-1</sup>s<sup>-1</sup> and the value is still far from being enough for large scale displays. The instability of transport properties of ZnO TFTs under the light irradiation is also critical. Recently, it was reported that the incorporation of nitrogen into ZnO films significantly improved the electronic mobility and photostability [1]. Therefore, we suggest atomic layer deposition (ALD) of  $ZnO_xN_y$  films for the improvement of the electrical properties. ALD is a thin film growth technique for high quality thin films with a precise thickness control and composition control at a relatively low temperature, which facilitates TFTs on large area flexible substrates. We deposited  $ZnO_xN_y$ films by ALD with DEZ, H<sub>2</sub>O and NH<sub>3</sub> at 150 °C. For controlling the incorporation of nitrogen into ZnO, a cycle ratio (R<sub>H2O/NH3</sub>) of [DEZ-H<sub>2</sub>O]:[DEZ-NH<sub>3</sub>] varied from 1:0 to 1:9. A growth per cycle of the ZnO films increased with R<sub>H2O/NH3</sub> despite no formation of Zn<sub>3</sub>N<sub>2</sub> by ALD at this temperature. This might result from the easy chemisorption of NH<sub>3</sub> on the ZnO surface. The optical band-gap was controlled even at a very low  $R_{H20/NH3}$ . Also, electrical properties of  $ZnO_xN_y$  films were changed systematically by the variation in the R<sub>H2O/NH3</sub>. In the presentation, we will report the detailed optical- and electrical properties of ZnO<sub>x</sub>N<sub>y</sub> and the transport properties of TFTs using the ZnO<sub>x</sub>N<sub>y</sub> films.



Fig. 1. Optical absorption spectra of the ZnO<sub>x</sub>N<sub>y</sub> films grown at the R<sub>H2O/NH3</sub> range from 1:0 to 1:9

Reference

1. E. H. Lee, A. Benayad, T. H. Shin, H. G. Lee, D. S. Ko, T. S. Kim, K. S. Son, M. K. Ryu, S. H. Jeon, G. S. Park, *Scientific reports*, 4, 4948 (2014).